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REPLY UNDER 37 CFR 1.116 APR 14 2006
EXPEDITED PROCEDURE
TECHNOLOGY CENTER 2800

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of: Anderson *et al.* Conf. No.: 1115
Serial No.: 10/604,116 Art Unit: 2823
Filed: 06/26/2003 Docket No.: BUR920030031US1 (IBMB-0028)
Examiner: Joannie A. Garcia

Title: METHOD OF FORMING
FREESTANDING SEMICONDUCTOR
LAYER

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AFTER FINAL REQUEST FOR RECONSIDERATION

Sir:

INTRODUCTORY COMMENTS

In response to the Final Office Action of February 16, 2006, please re-consider the
rejections based on the following remarks.